## Wafer-size growth of 2D layered SnSe films for UV-Visible-NIR

## Photodetector Arrays with High Responsitivity

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**Fig. S1** a) Dynamic response curves under 404-nm laser with 15.5 mWcm<sup>-2</sup> from five different devices. (b) The rms noise for the devices

The root-mean-square (RMS) noise was calculated from the dark currents of the above five devices based on the following equation,<sup>1</sup>

$$RMS_{noise} = \sqrt{\sum (I - I_0)^2 / N}$$
<sup>(1)</sup>

where *I* is measured dark current depending on time,  $I_0$  is the initial dark current before illumination, and *N* is the number of data points. As shown Fig. R1b (new Fig. S1b in Supporting Information), the RMS noise for different devices has little deviation of  $5.2 \sim 7.8$  nA, and its mean is  $6.18\pm1.00$  nA, which are much smaller than that of the light current (abut 2  $\mu$ A), indicating the high electric noise homogeneity.



**Fig. S2** Comparison between the original and 3-month response curve. The RMS currents of original and 3-month-age are 6.9 nA and 8.7 nA, respectively, further revealing the high stability of the fabricated photodetector.

Notes and referrence

1 C. Yim, K. Lee, N. McEvoy, M. Brien, S. Riazimehr, N. Berner, C. Cullen, J. Kotakoski, J. Meyer, M. Lemme, G. Duesberg, ACS Nano 2016, 10, 9550.